

PATENT APPLICATION Docket No. 11675.114

>) Group Art) Unit 1763

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Kei-Yu Ko

Serial No.:

08/846,671

Filed:

April 30, 1997

For:

UNDOPED SILICON DIOXIDE AS ETCH

STOP

FOR SELECTIVE ETCH OF DOPED SILICON DIOXIDE

Examiner:

George A. Goudreau

AMENDMENT "E" AND RESPONSE

The Honorable Commissioner of Patents and Trademarks
Washington, D. C. 20231

Sir:

In response to the Office Action dated on January 18, 2002 (the "Office Action"), Applicant submits this Amendment "E" and Response. Please amend the above-identified application as follows:

IN THE CLAIMS:

CLEAN VERSION OF THE PENDING CLAIMS Under 37 C.F.R. § 1.121(c)(3):

Please amend the claims as indicated below so that the following list presents a clean version of the entire set of pending claims.

Amendment "E" and Response Serial No.08/846,671